

## ABSTRACT

A substrate processing apparatus capable of readily addressing an increase/decrease in quantity of substrates to be processed and a change in type thereof. The substrate processing apparatus includes a carrier block having a first transfer device performing delivery of the substrate with respect to a substrate carrier on a carrier placement portion, a transfer block provided adjacent to the carrier block and having a second transfer device, a first delivery stage performing delivery of the substrate between the first transfer device and the second transfer device, and a plurality of process blocks freely attachable/detachable with respect to the transfer block. Since the process blocks perform a series of processing on the substrate in units of the process blocks, it is readily possible to address considerable increase/decrease in quantity of processed substrates by attaching/detaching the process block(s), and to address the different change in type thereof by changing the process block(s).